



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No. 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Not Yet Assigned

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

**SUBMISSION OF CORRECTED VERSION OF PCT NOTIFICATION
CONCERNING PRIORITY DATA**

Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicants submit herewith Form PCT/IB/304 for PCT Application No. PCT/JP01/06164 (assigned Application No. 10/088,306) and the Corrected Version of the front page of the PCT application. The corrected PCT Notification corrects the filing date of JP 2000-397269 from which Applicant's claim foreign priority under 35 U.S.C. § 119. The correct priority date is reflected in Applicants' Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

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